

| | | | |
|---|--|---------------------------------------|-------------------------------|
| Substitute Form PTO-1449 (Modified) | U.S. Department of Commerce Patent and Trademark Office | Attorney's Docket No. 10559-893001 | Application No. 10/789,670 |
| Information Disclosure Statement by Applicant (Use several sheets if necessary) | | Applicant Arun Ramamoorthy et al. | |
| | | Filing Date February 27, 2004 | Group Art Unit 1724 |

(37 CFR §1.98(b))

U.S. Patent Documents

| Examiner Initial | Desig. ID | Document Number | Publication Date | Patentee | Class | Subclass | Filing Date If Appropriate |
|------------------|-----------|-----------------|------------------|----------|-------|----------|----------------------------|
| | AA | | | | | | |
| | AB | | | | | | |
| | AC | | | | | | |
| | AD | | | | | | |
| | AE | | | | | | |
| | AF | | | | | | |
| | AG | | | | | | |
| | AH | | | | | | |
| | AI | | | | | | |
| | AJ | | | | | | |
| | AK | | | | | | |

Foreign Patent Documents or Published Foreign Patent Applications

| Examiner Initial | Desig. ID | Document Number | Publication Date | Country or Patent Office | Class | Subclass | Translation | |
|------------------|-----------|-----------------|------------------|--------------------------|-------|----------|-------------|----|
| | | | | | | | Yes | No |
| | AL | | | | | | | |
| | AM | | | | | | | |
| | AN | | | | | | | |
| | AO | | | | | | | |
| | AP | | | | | | | |

Other Documents (include Author, Title, Date, and Place of Publication)

| Examiner Initial | Desig. ID | Document |
|------------------|-----------|---|
| | AQ | Chauhan, M.M., et al., "Photoresist Outgassing in EUV", 2000 March Meeting: Bulletin of the American Physical Society, 45(1):563, abstract #L36.112, March 2000. |
| | AR | Moors, R., et al., "Electrostatic mask protection for extreme ultraviolet lithography", <i>Journal of Vacuum Science & Technology B: Microelectronics and Nanometer Structures</i> , 20(1):316-320, Jan/Feb 2002. |
| | AS | |
| | AT | |

| | |
|--|----------------------------|
| Examiner Signature /Ives Wu/ | Date Considered 05/10/2008 |
| EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | |

Substitute Disclosure Form (PTO-1449)

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. //I.W./